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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

**SECOND SUPPLEMENTAL INFORMATION
DISCLOSURE STATEMENT BY APPLICANT**

Atty. Docket No.

UBAT1520

Applicant
Gregory R. Hanson et al.

Application Number

10/649,474

Filed

August 26, 2003

For
**Spatial Heterodyne Interferometry for Reflection
and Transmission (SHIRT) Measurements**

Group Art Unit

2877

Examiner

Connolly, Patrick J

Certificate of Mailing Under 37 C.F.R. 1.8

I hereby certify that this correspondence is being deposited with the U.S. Postal Service as First Class Mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on Aug 24, 2005.

John J. Bruckner

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

The PTO did not receive the following listed item(s): A check for \$180.00

Applicants respectfully request, pursuant to 37 C.F.R. §§ 1.56, 1.97 and 1.98, that the art listed on the attached PTO-1449 form be considered and cited in the examination of the above-identified application. A copy of the art is enclosed for the convenience of the Examiner. Furthermore, pursuant to 37 C.F.R. §§ 1.97(g) and (h), no representation is made that a search has been made or that this art is material to patentability of the present application. Copies of the non-US patent references are enclosed for the convenience of the Examiner.

This Information Disclosure Statement is being filed after mailing of a First Office Action. Applicant hereby requests consideration of this Information Disclosure Statement pursuant to 37 C.F.R. § 1.97(c)(2). A check in the amount of \$180 representing the fee set forth in 37 CFR § 1.17(p) is enclosed.

While Applicants believe no (further) fees are due, if any (further) fees are due, the Commissioner is hereby authorized to charge any fees or credit any overpayments to Deposit Account No. 50-3204 of John Bruckner PC.

Dated: Aug 24, '05

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Respectfully submitted,
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Attorneys for Applicant

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The PTO did not receive the following listed item(s): A check for \$180.00

INFORMATION DISCLOSURE

STATEMENT BY APPLICANT

Application Number

10/649,464

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First Named Inventor

Gregory R. Hanson

Group Art Unit

2877

Examiner Name

Connolly, Patrick J

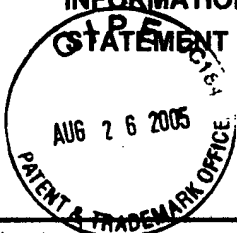
Attorney Docket

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Examiner Initials	Cite No.	Document Number		Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document
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		Country Code	Number		
		JP	06282213	07/10/1994	Citizen Watch Co. Ltd.
Examiner Signature				Date Considered	

INFORMATION DISCLOSURE STATEMENT BY APPLICANT 		Application Number	10/649,474
		Filing Date	August 26, 2003
		First Named Inventor	Gregory R. Hanson et al.
		Group Art Unit	2877
		Examiner Name	Connolly, Patrick J
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Examiner Signature		Date Considered

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				First Named Inventor	Gregory R. Hanson	
				Group Art Unit	2877	
				Examiner Name	Connolly, Patrick J	
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